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PATENT  
ATTORNEY DOCKET NO. 042715-5020

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:

**Yasuhiro Takaki**

Application No.: 10/582,101

Filed: June 8, 2006

For: PATTERN FORMATION METHOD USING )  
NANOIMPRINTING AND DEVICE FOR )  
CARRYING OUT SAME )

Confirmation No. 1159

Group Art Unit: 1792

Examiner: R. Culbert

**Mail Stop Amendment**

Commissioner for Patents  
U.S. Patent and Trademark Office  
**Mail Stop Amendment**  
Alexandria, VA 22314

Sir:

**RESPONSE TO ELECTION/RESTRICTION REQUIREMENT**

In response to the Election/Restriction Requirement under 35 U.S.C. § 121 dated February 4, 2008 (Page No. 0208), the Examiner required an election of a single disclosed invention under 35 U.S.C. § 121 between: invention I, allegedly drawn to a method of patterning a resist, corresponding to claims 1-21; and Invention II, allegedly drawn to a patterning apparatus, corresponding to claims 22-24.

In response to the Election and Restriction Requirement set forth in the Office Action, Applicant hereby elects Invention I including claims 1-21 without traverse. Accordingly, Applicant respectfully requests formal examination of this application. In addition, Applicant reserve the right to file divisional applications directed to the non-elected claims.